

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant: YI et al. Examiner: Watson, Joy L.

Serial No.: 10/827,512 Group Art Unit: 1709

Filed: April 19, 2004

For: **APPARATUS AND METHOD FOR CLEANING  
SEMICONDUCTOR SUBSTRATES**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**RESPONSE TO RESTRICTION REQUIREMENT**

Sir:

In response to the Office Action dated June 12, 2007, Applicants provisionally elect the claims of Group II (i.e., claims 8-26).

While the method of Group I and the apparatus of Group II may be distinct as set forth by the Examiner, Applicants believe that simultaneous examination will not present an undue burden. For example, the claims of Group I are drawn to the method for cleaning semiconductor substrates, and the claims of Group II are drawn to the apparatus for cleaning semiconductor substrates. The subject matter of the two claim groups can be found in class 134. Under such circumstances, the Examiner is encouraged to maintain the claims of Groups I and II in the same application. See, MPEP § 803.

Early and favorable consideration of the application is earnestly solicited.

Respectfully submitted,



---

Frank Chau  
Reg. No. 34,136  
Attorney for Applicant

F. CHAU & ASSOCIATES, LLC  
130 Woodbury Road  
Woodbury, NY 11797  
Telephone: (516) 692-8888  
Facsimile: (516) 692-8889